IN THE CLAIMS

- (currently amended) A method for analyzing defect information on a substrate, the method comprising the steps of:
 - inspecting the substrate to identify individual defect events, including at least one of defects, defective pixels, and defective defensive dice,
 - classifying the individual defect events into event patterns, include-including at least one of defect clusters and spatial signatures,
 - comparing the event patterns to a list of patterns of interest,
 - logically dividing the substrate into zones,
 - identifying the zones in which the patterns of interest exist on the substrate,
 - comparing the identified zones to a list of zones of interest,
 - identifying combinations of (1) patterns of interest on the substrate that (2) reside within zones of interest on the substrate, and
 - comparing the identified combinations to a list of predetermined combinations that are associated with defect causes, and
 - specifying at least one substrate defect cause based at least in part on matches between the identified combinations and the predetermined combinations and the associated defect causes.
- 2-20 (canceled)

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